Product Description

High Resolution High Accuracy AFM Cantilevers HA_CNC series are designed for Semicontact (Intermittent), Noncontact applications. Each probe has 2 rectangular cantilevers.Typical Resonant Frequency 66kHz / 46kHz (dispersion ±10%). Typical Force Constant 1.5N/m / 1.0N/m (dispersion ±20%). Cantilever has Au reflective side coating to increase laser signal. Probes are also available with no coating as well as with conductive tip coating.

Probes are packed in boxes with 15 and 50 pieces. Amount discount is included in the package price.

High Accuracy composite ETALON probes combine the main features allowing to obtain high quality AFM images:

- Sharp tip - curvature radius < 10 nm.
- Resonance frequency, specified with high accuracy - ±10% within a wafer.
- Special chip geometry with vertical sidewalls for convenient operating.
- High aspect ratio tip.
- Enhanced back-side reflection of the cantilever.
- Cost effective price.

General Features

Material	Polysilicon cantilever, silicon tip
Chip size	3.6x1.6x0.4mm
Reflective side coating	Au
Tip coating	No
Tip curvature radius	< 10nm
Available tip coatings	Pt, Au

Special Features

Cantilever series	Cantilever	Cantilever length, L±2μm	Cantilever width, W±3μm	Cantilever thickness, T±0.15μm	Resonant frequency, kHz			Force constant, N/m		
					min	typical	max	min	typical	max
HA_CNC	A	224	34	1.85	41	46	51	0.8	1.0	1.2
	B	184	34	1.85	59	66	55	1.2	1.5	1.8